

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET
NO. 35523US1SERIAL NO.
10/825,504INFORMATION DISCLOSURE CITATION
BY APPLICANT

APPLICANT: Volker Derflinger et al.

FILING DATE:
April 15, 2004GROUP ART UNIT:
3722

U.S. PATENT DOCUMENTS

| Examiner Initial | | Document No. | Date | Name | Class | Subclass | Filing Date if Appropriate |
|------------------|---|--------------|------|------|-------|----------|----------------------------|
| | A | | | | | | |
| | B | | | | | | |
| | C | | | | | | |
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FOREIGN PATENT DOCUMENTS

| | | Document No. | Date | Country | Class | Subclass | Translation |
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| | H | 1 186 681 A1 | 8/2001 | EP | | | Cited in Spec. |
| | I | 09-041127 | 8/1995 | JP | | | Cited in Spec. |
| | J | | | | | | |
| | K | | | | | | |

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| | R | Thin films (Proc. 4 in. Sympos. Trends & New Applications of Thin Films 1993) DGM Info. Sges., Oberursel 1993, p 73. |
| | S | Surface & Coatings Technology vol. 165, 2 (2003) p. 163-167. Oxidation Resistance of Cr _{1-x} Al _x N and Ti _{1-x} Al _x N films. |
| | T | Surface & Coating Technology vol. 163-164 (2003) p. 57-61. High-Temperature Oxidation Resistance of Cr _{1-x} Al _x N Thin Films Deposited by Reactive Magnetron Sputtering. |
| | U | J. Vac. Sci. Technol. A 20(2), Mar/Apr 2002, p. 569-571. Microhardness and Lattice Parameter of Cr _{1-x} Al _x N Films. |
| | V | Surface & Coating Technology, vol. 163-164 (2003) p. 546-551. Abrasive Wear Tsting of DLC Coatings deposited on plane and Cylindrical Parts. |
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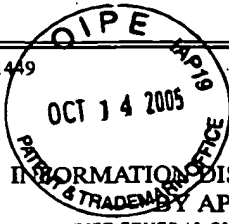
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| Form PTO-1449 <div style="text-align: center;">  </div> | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY. DOCKET NO. 35523US1 | | SERIAL NO. 10/825,504 | |
| INFORMATION DISCLOSURE CITATION BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY) | | | | APPLICANT: Volker Derflinger et al. | | | |
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| U.S. PATENT DOCUMENTS | | | | | | | |
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| Examiner Initial | Document No. | Date | Name | Class | Subclass | Filing Date If Appropriate | |
| A | A | 2003/0035894 A1 | 02/2003 | Derflinger et al. | | | |
| | B | | | | | | |
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| | K | 1 422 311 A2 | 11/2003 | Europe | | | English Text |
| | L | 1 422 311 A3 | 11/2003 | Europe | | | English Abstract |

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| A | M F. Sanchette, A. Billard, C. Frantz, "Mechanically reinforced and corrosion-resistant sputtered amorphous aluminium alloy-coatings", Surface and Coatings Technology 98 (1998), pages 1162-1168. |
| N | J. Vetter, E. Lugscheider, S.S. Guerreiro, "(Cr:Al) N Coatings deposited by the cathode vacuum arc evaporation", Surface and Coatings Technology 98 (1998), pages 1233-1239. |
| O | Clemens Kunisch, Ronald Loos, Michael Stuber and Sven Ulrich, "Thermodynamic modeling of Al-Cr-N thin film systems grown by PVD", 1999, pages 847-852. |
| P | Y. Ide, T. Nakamura and K. Kishitake, "Formation of Al-Cr-N films by a DC reactive sputtering method and evaluation of their properties", 2000, pages 291-296. |

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